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TABLE OF CONTENTS

Monday, 13 August 2007

PLE	Plenary Session	
PLE1	Concepts of Nanophotonic Devices and Fabrications	1
PLE2	Combination of MEMS and Microoptics for New Application.....	N/A
PLE3	Photonic Band Gap Materials: Engineering Light-Matter Interactions	3
MA	Medical and Bio Sensing	
MA1	Wearable Laser Blood Flowmeter for Ubiquitous Healthcare Service	4
MA2	A Portable Two-Photon Fluorescence Microendoscope based on a Two-Dimensional Scanning Mirror.....	6
MA3	Tunable Endoscopic MEMS-Probe for Optical Coherence Tomography.....	8
MA4	Forward-Imaging Swept Source Optical Coherence Tomography using Silicon MEMS Scanner for High-Speed 3-D Volumetric Imaging	10
MA5	Miniaturized Optical Viscosity Sensor based on a Laser-induced Capillary Wave	12
MB	Active Nano Devices	
MB1	High-Q Photonic Crystal Nanocavities	14
MB2	Modeling of Slow Light in Vertical Cavity Surface Emission Lasers	15
MB3	A Nano-scale Nanocrystal Photodetector with High Sensitivity	17
MB4	Waveforms of Terahertz Radiation Emitted from Superconducting Dipole Antenna	19
MB5	Loss and Crosstalk in Quantum Dot Waveguides.....	21
MC	Novel Fabrication Techniques	
MC1	Towards the Fabrications Platforms for MOEMS	23
MC2	FR-4 as a New MOEMS Platform	25
MC3	Optically Flat Micromirror Using Stretched Membrane with Crystallization-Induced Stress	27
MC4	Polarization-Transmissive Thin-Film Solar Cell with Photodiode Nanowires.....	29
MC5	Micro Knife-Edge Optical Measurement Devices Fabricated by SOI and CMOS MEMS Processes	31

Tuesday, 14 August 2007

TuA	Bio Nano Devices	
TuA1	Linear Tactile Nanodevice with Resolution on Par with Human Finger	35
TuA2	Optical NEMS Based Force Sensor Using Silicon Nanophotonics.....	37
TuA3	Photostable Single KTiOPO ₄ Nanocrystals for Second-Harmonic Generation Microscopy	39
TuA4	Iridescent Photonic Nano-Silica for Chemical and Biological Sensing	41
TuA5	A Novel Single-Cell Surgery Tool Using Photothermal Effects of Metal Nanoparticles.....	43
TuB	Actuation	
TuB1	Optically Controlled, Holographic Micro-Hand	45
TuB2	A Thermo-Pneumatically Actuated Tip-Tilt-Piston Mirror	47
TuB3	Bi-directionally Driven Metal Cantilevers Developed for Optical Actuation.....	49
TuB4	Reconfigurable Nanophotonic Systems by Tunable Alignment between Nanomagnet Arrays.....	51
TuB5	High-Accuracy Digital-to-Analog Actuators Using Parallel Spring Array.....	53
TuP	Poster Session	
TuP1	Novel Large Area Applications Using Optical MEMS.....	55
TuP2	Characterization of an Improved, Real-Time MEMS-Based Phase-Shifting Interferometer.....	57
TuP3	Fast Tracking of Light Source with Micromirror and Associated Feedback Circuit.....	59
TuP4	Parallel and Selective Trapping in a Patterned Plasmonic Landscape.....	61
TuP5	Laser Doppler Vibrometer Using a 45°-Angled Optical Fiber for In-Plane Dynamic Measurement of MEMS Actuators.....	63

TuP6	A Dielectrically Driven Liquid Lens with Optical Packaging	65
TuP7	Fully-Integrated Optofluidic Trap with Linear Microsphere Array	67
TuP8	Electrowetting-Based Total Internal Reflection Chip for Optical Switch and Display.....	69
TuP9	Self-Alignment Micro-Lens by Gradient of Surface Tension	71
TuP10	Design of a Holding System for Micro-Coil based MRI	73
TuP11	Glass Reflowed Microlens Array and its Optical Characteristics	75
TuP12	Photothermally Actuated Microcantilever Beams Using Nanoparticles	77
TuP13	Vertical Comb-Drive MEMS Mirror for Optical Spectrum Sensing	79
TuP14	Drift-Free Single Crystalline Silicon Micromirror with Floating Field Limiting Shields.....	81
TuP15	A Two-Axis MEMS Scanner Driven by Radial Vertical Combdrive Actuators	83
TuP16	Pull-in Analysis of Scanners Actuated by Electrostatic Vertical Combdrives	85
TuP17	Micromirrors for Multiobject Spectroscopy: Large Array Actuation and Cryogenic Compatibility.....	87
TuP18	Improved Control of the Vertical Axis Scan for MEMS Projection Displays.....	89
TuP19	High Temperature Operation of Gimbal-less Two Axis Micromirrors.....	91
TuP20	Mechanical-Contact-Based Submicron-Si-Waveguide Optical Microswitch at Telecommunication Wavelengths.....	93
TuP21	Two-Wavelength Grating Interferometry for Extended Range MEMS Metrology	95
TuP22	A New Fast Infrared Tracking System with Thermopile Array Implementation	97
TuP23	Self-Supported Pitch-Variable Guided-Mode Resonant Grating Filters at Telecom Wavelengths	99
TuP24	An Optical MEMS Pressure Sensor based on Phase Demodulation.....	101
TuP25	A MEMS-based Organic Deformable Mirror with Tunable Focal Length	103
TuP26	Novel Adaptive Optics System with an Electrostatically-Driven Deformable Mirror and Wavefront Compensation Algorithm.....	105
TuP27	Reflectance Study of Nano-Scaled Textured Surfaces.....	107
TuP28	Experimental Observation of Self-Propelled Cavity Soliton-like Evolutions in VCSELs with Photonic-Crystal Micro-Structures	109
TuP29	Elastic-like Collision of Gap Solitons in Nonlinear Nonlocal Photonic Crystals	111
TuP30	Wide-Angle Low-Loss 1×2 Multimode Interference Optical Power Divider with Tilted Input and Output Waveguides	113
TuP31	Double Reflection in the Blazed Grating	115
TuP32	Effect of a Vertical Stack of Aligned Subwavelength Metal Hole Arrays on Extraordinary Transmission Spectra	117
TuP33	The Measurement of Liquid Refractive Index by D-Shaped Fiber Bragg Grating	119
TuP34	A Compact Silicon-on-Insulator MMI-based Polarization Splitter	121
TuP35	Near-Field Images of Surface Plasmon Eigenmodes in Gold Nanogratings	123
TuP36	Surface Plasmon Leakage in Its Coupling with an InGaN/GaN Quantum Well through an Ohmic Contact.....	125
TuP37	Temperature-dependent Behaviors of the Surface Plasmon Coupling with an InGaN/GaN Quantum Well	127
TuP38	The Role of the Quantum-Confined Stark Effect in an InGaN/GaN Quantum Well During Its Coupling with Surface Plasmon for Light Emission Enhancement.....	129
TuP39	Passivation of Silicon Wafer Patterned by Aluminum for Micromachining.....	131

Wednesday, 15 August 2007

WA Microlenses

WA1	MEMS-based Microspectrometers for Infrared Sensing	137
WA2	Fabrication and Characterization of a Repositionable Liquid Micro Lens System.....	139
WA3	A Lateral-shift-free LVD Microlens Scanner for Confocal Microscopy	141
WA4	Implementation of CMOS-MEMS Compound Lens	143
WA5	Low Cost Adaptive Silicone Membrane Lens.....	145

WB Micro and Nano Lithography

WB1	Vortex Generation and Pixel Calibration Using a Spatial Light Modulator for Maskless Lithography	147
WB2	The Study on 3D Electron Beam Lithography for Sub-Micrometer Diffractive Optics	149

WB3	Fabrication of a Multi-Level Lens Using Independent-Exposure Lithography and FAB Plasma Etching	151
WB4	Self-Assembled Two-Dimensional Block Copolymers on Pre-Patterned Templates with Laser Interference Lithography.....	153
WB5	Fabrication of Large Size Photonic Crystal Templates by Holographic Lithography Technique	155
WB6	Extraordinary Transmission Through A Poly-SiC Membrane with Subwavelength Hole Arrays	157
WC	Spectroscopy	
WC1	Compact Spectroscopic Sensor Using an Arrayed Waveguide Grating	159
WC2	A Micro-Optic-Fluidic Spectrometer with Integrated 3D Liquid-Liquid Waveguide	161
WC3	A Disposable Grating-integrated Multi-channel SPR Sensor Chip for Real-time Monitoring of Biomolecule Binding	163
WC4	Tunable Resonant Cavity Enhanced Detectors using Vertical MEMS Mirrors	165
WC5	Two-state Optical Filter Based on Micromechanical Diffractive Elements.....	167
WD	Tunable Devices	
WD1	MEMS Tunable Filters for LWIR Spectral Imaging	169
WD2	Tunable Erbium Doped Fiber Laser Using a Silicon Micro-Electro-Mechanical Fabry-Perot Cavity	171
WD3	Design and Fabrication of Photonic MEMS Waveguide Modulators	173
WD4	A Study on Optical Diffraction Characteristics of Skewed MEMS Pitch Tunable Gratings	175
WD5	Tunable MEMS Actuated Microring Resonators	177

Thursday, 16 August 2007

ThA	Nanofabrication	
ThA1	One-Way Waveguide and Strong Photon-Photon Interaction in Nanophotonic Structures	181
ThA2	Flower-Structured InGaN/GaN Quantum-Well Nanodisk Crystals on Micromachined Si Pillars	183
ThA3	Fabrication of Wafer-level Antireflective Structures in Optoelectronic Applications	185
ThA4	Structural and Optical Properties of III-V Nanowires and Nanowire Heterostructures Grown by Metalorganic Chemical Vapour Deposition.....	187
ThA5	Magnetic Alignment of Carbon Nanotube Interconnects	189
ThB	Micromirrors	
ThB1	Optical MEMS for Future Instruments in Astronomy.....	191
ThB2	Passivated Piezoresistive Rotation Angle Sensor Integrated in Micromirror	193
ThB3	Integrated Piezoresistive Positionsensor for Microscanning Mirrors.....	195
ThB4	Ultra Flat High Resolution Microscanners	197
ThB5	Combined Device of Optical Microdisplacement Sensor and PZT-Actuated Micromirror	199
Author Index		201